7th International Symposium on Laser Precision Microfabrication

LPM2007

http://www.jlps.gr.jp/lpm/lpm2007/

24. - 28. April 2007, University of Vienna, Vienna, Austria

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Organizers:

JLPS, Japan Laser Processing Society, Japan
University of Vienna, Department of Physical Chemistry, Vienna, Austria
Austrian Laser Association (ARGELAS), Vienna, Austria
Vienna University of Technology, Department for Forming and High Power Laser Technology, Austria
AIST, National institute of Advanced Industrial Science and Technology, Japan
RIKEN, The Institute of Physical and Chemical Research, Japan

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Aim and Scope:

Miniaturization and high precision are rapidly becoming a requirement on many industrial processes and products. As result, there is greater interest in the use of laser micro/nanofabrication approaches to achieve these goals. The International Symposium on Laser Precision Microfabrication (LPM) is annually held to provide a forum for research and technology development in the area of laser micro/nanofabrication. The topics encompass novel developments in hardware, software and in the fundamental chemistry/physics that buttress laser material interaction processes. The unique aspect of this conference is the interchange between fundamental research and industrial applications.

LPM is held in Japan in even years and in other host countries in odd years. To date, LPM has been successfully hosted in Omiya/Japan (2000), Singapore (2001), Osaka/Japan (2002), Munich/Germany(2003), Nara/Japan (2004), Williamsburg/USA (2005), and Kyoto/Japan (2006).

The aim of LPM2007 is to provide a forum for discussion on the fundamental aspects of laser/material interaction, the state of the art of laser materials processing and the germination of next-generation ideas that arises from collaborating scientists, end users and laser manufacturers. The LPM2007 Proceedings will be published online. We extend a welcome and hope that you will join us at LPM2007.



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University of Vienna Lecture Hall

LPM Topics:

- 1. Fundamental aspects (Dynamics, modelling, simulation, etc.)
- 2. Process monitoring and control
- 3. Laser- and Photochemistry
- 4. Nanotechnology
- 5. Ultra-short pulse laser processing
- 6. VUV laser and X-ray processing
- 7. Advanced laser processing (fibre laser, disc laser, FEL, etc.)
- 8. Surface treatment (Texturing, cleaning, annealing, modification, etc.)
- 9. Micro-patterning and micro-structuring
- 10. Micro-machining
- 11. 3-D micro- and nano-fabrication
- 12. Laser-based direct-write techniques
- 13. Glass/Ceramic processing
- 14. Drilling and cutting

- 15. Welding and bonding
- 16. Micro-forming
- 17. Wafer dicing
- 18. Marking and trimming
- 19. Packaging and mounting process
- 20. Lithography
 - (including EUV source and application)
- 21. Manufacture of micro devices and systems
- 22. Film deposition and synthesis of advanced materials (PLD, CVD, etc)
- 23. Nano- and micro-particles
- 24. Medical and biological applications
- 25. Optics and systems for laser microprocessing
- 26. Laser devices
- 27. Industrial applications
- 28. Others

Tourist and logistics organization:

Vienna Convention Bureau (www.vienna.convention.at)

Vienna, Austria:

www.wien.gv.at/english/ www.info.wien.at









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